

**PLENARY SESSIONS**

	AUTHORS		TITLE
PL-25	<b>M. Wada</b>		Laser based plasma and surface diagnostics for negative hydrogen ion sources
PL-68	<b>H.J. Ramos</b>		Plasmas for instrumentation, academic training and innovative applications
PL-39	<b>M. Sasao</b>	M. Wada	Probing beams for plasma diagnostics and their applications to plasma process devices and surface modification
PL-60	<b>S. Hamaguchi</b>	K. Karahashi	Atomic-scale analyses of non-equilibrium surface chemical reactions in dry etching processes for modern semiconductor devices
PL-66	<b>D.T. Quinto</b>		Plasma assisted surface treatments and manufacturing productivity for developing economies
PL-62	<b>J. Greene</b>		Fundamental properties of TM nitrides: materials design strategies for extreme properties
PL-64	<b>S.K. Guharay</b>		Negative ions for emerging interdisciplinary applications
PL-69	<b>D.N. Ruzic</b>		The plasma-material interactions in plasma cleaning